## **Technical Data Sheet**

## **Silicone Test Specimen**

## #79502

The test specimen consists of lines etched into a single crystal silicon substrate, written by electron beam machinery. It consists of a square mesh of course lines of  $500\mu m$  spacing with 50 intermediate fine lines of  $10\mu m$  spacings.

The 10µm pitch has been measured using an automatic line width measuring system.

Position	Pitch Meas. µm
1	10.004
2	9.997
3	9.989
	10.004
5	9.997
6	9.988
7	9.982
8	10.001
9	9.969
10	9.953
11	9.975
12	9.986
13	9.944

## **Measurement Stats**

Max	10.004
Min	9.944
Mean	9.984

0.02

Standard Deviation